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Attorney Docket No. A-67736-1/MSS (463035-19)

PATENT

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Signed:


Kari Bateman Aguilar

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
SAVAGE et al.

Serial No.: **09/767,659**

Filed: **January 22, 2001**

For: **Semiconductor wafer processing
system with vertically-stacked
process chambers and single-axis
dual-wafer transfer system**

Examiner: **FOX, CHARLES A**

Art Unit: **3652**

Confirmation No.: **2896**

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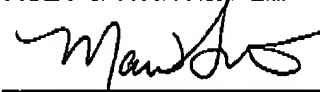
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